

CLAIMS

What is claimed is:

- 1 ✓ 1. A method of coupling one or more surface-emitting lasers to one or more edge-receiving
2 optical devices, the method comprising the steps of:
3 mounting the one or more surface-emitting lasers to an optical bench substrate;
4 mounting the one or more edge-receiving optical devices to the optical bench substrate;
5 and
6 emitting output signals from the one or more surface-emitting lasers to the one or more
7 edge-receiving optical devices.
- 1 — 2. The method of claim 1, wherein the one or more surface-emitting lasers are fabricated on
2 a laser substrate; and wherein the step of mounting the one or more surface-emitting lasers
3 comprises the step of mounting the laser substrate to a slot on the optical bench substrate so that
4 the output signals emit directly into the one or more edge-receiving optical devices.
- 1 — 3. The method of claim 2, wherein the step of mounting the laser substrate comprises the
2 step of mounting an edge of the laser substrate to the slot so as to optically couple the one or
3 more surface-emitting lasers to the one or more edge-receiving optical devices.
- 1 ✓ 4. The method of claim 1, wherein the optical bench substrate defines one or more
2 alignment features for aligning the laser substrate and the one or more edge-receiving optical
3 devices together so as to optically couple the one or more surface-emitting lasers to the one or
4 more edge-receiving optical devices.
- 1 — 5. The method of claim 2, wherein the slot is photolithographically fabricated in the optical
2 bench substrate.
- 1 — 6. The method of claim 2, wherein the slot is fabricated in the optical bench substrate using
2 electron beam lithography.
- 1 ✓ 7. The method of claim 4, wherein the alignment features are photolithographically
2 fabricated in the optical bench substrate.

1 ✓8. The method of claim 4, wherein the alignment features are fabricated in the optical bench
2 substrate using electron beam lithography.

1 →9. The method of claim 2, wherein the step of mounting the laser substrate comprises the
2 step of mounting the laser substrate to the slot on the optical bench substrate by one of solder and
3 epoxy.

1 ✓10. The method of claim 1, wherein the step of mounting the one or more edge-receiving
2 optical devices comprises the step of mounting the one or more edge-receiving optical devices
3 on the optical bench substrate by one of solder and epoxy.

1 ✓11. The method of claim 1, wherein the step of mounting the one or more edge-receiving
2 optical devices comprises the step of monolithically fabricating the one or more edge-receiving
3 optical devices on the optical bench substrate. *mounting and fabricating on same substrate*

1 ✓12. The method of claim 1, wherein the one or more surface-emitting lasers comprise an
2 array of lasers and the one or more edge-receiving optical devices comprise an array of edge-
3 receiving optical devices.

1 ✓13. The method of claim 1, wherein the one or more edge-receiving optical devices comprise
2 one or more edge-receiving optical modulators.

1 ✓14. The method of claim 1, wherein the one or more edge-receiving optical devices comprise
2 one or more edge-receiving optical amplifiers.

1 ✓15. The method of claim 13, wherein the one or more edge-receiving optical devices further
2 comprise one or more edge-receiving optical amplifiers positioned in the path of the output
3 signals from the one or more edge-receiving optical modulators.

1 ✓16. The method of claim 14, wherein the one or more edge-receiving optical devices further
2 comprise one or more edge-receiving optical modulators positioned in the path of the one or
3 more output signals from the one or more edge-receiving optical amplifiers.

1 17. The method of claim 1, wherein the one or more edge-receiving optical devices are
2 semiconductor optical amplifiers (SOAs).

1 18. The method of claim 1, wherein the one or more edge-receiving optical devices are
2 optical waveguides.

1 19. The method of claim 1, wherein the one or more surface-emitting lasers are vertical-
2 cavity surface-emitting lasers (VCSELs).

1 20. The method of claim 1, wherein the optical bench substrate further comprises, for each
2 edge-receiving optical device, a driver circuit coupled to the edge-receiving optical device.

1 21. The method of claim 1, wherein the optical bench substrate is a silicon optical bench.

1 22. A method of conditioning the output signals of one or more surface-emitting lasers, the
2 method comprising the steps of:

3 mounting the one or more surface-emitting lasers to an optical bench substrate having
4 one or more edge-receiving optical devices so as to optically couple the one or more surface-
5 emitting lasers to the one or more edge-receiving optical devices; and
6 coupling the output signals to the one or more edge-receiving optical devices.

1 23. The method of claim 22, wherein the one or more surface-emitting lasers are fabricated
2 on a laser substrate; and wherein the step of mounting the one or more surface-emitting lasers
3 comprises the step of mounting the laser substrate to a slot on the optical bench substrate so as to
4 optically couple the one or more surface-emitting lasers to the one or more edge-receiving
5 optical devices.

1 24. The method of claim 23, wherein the step of mounting the laser substrate comprises the
2 step of mounting an edge of the laser substrate to the slot so as to optically couple the one or
3 more surface-emitting lasers to the one or more edge-receiving optical devices.

1 ✓25. The method of claim 22, wherein the step of mounting the one or more surface-emitting
2 lasers comprises the step of mounting the one or more surface-emitting lasers to the optical
3 bench substrate by one of solder and epoxy.

1 ✓26. The method of claim 22, wherein the optical bench substrate defines one or more
2 alignment features for aligning the laser substrate and the one or more edge-receiving optical
3 devices together so as to optically couple the one or more surface-emitting lasers to the one or
4 more edge-receiving optical devices.

1 ✓27. The method of claim 22, wherein the one or more edge-receiving optical devices are
2 monolithically fabricated on the optical bench substrate.

1 ✓28. The method of claim 22, wherein the one or more edge-receiving optical devices
2 comprise one or more edge-receiving optical modulators.

1 ✓29. The method of claim 22, wherein the one or more edge-receiving optical devices
2 comprise one or more edge-receiving optical amplifiers.

1 ✓30. The method of claim 28, wherein the one or more edge-receiving optical devices further
2 comprise one or more edge-receiving optical amplifiers positioned in the path of the output
3 signals from the one or more edge-receiving optical modulators.

1 ✓31. The method of claim 29, wherein the one or more edge-receiving optical devices further
2 comprise one or more edge-receiving optical modulators positioned in the path of the output
3 signals from the one or more edge-receiving optical amplifiers.

1 32. A method of assembling a surface-emitting laser system comprising the steps of:
2 fabricating an array of surface-emitting lasers in a laser substrate;
3 providing an optical bench substrate having an array of edge-receiving optical devices;
4 and
5 mounting the laser substrate on the optical bench substrate so as to optically couple the
6 array of surface-emitting lasers to the array of edge-receiving optical devices.

1 33. The method of claim 32, wherein the step of providing an optical bench substrate
2 comprises the step of fabricating a slot for receiving an edge of laser substrate.

1 34. The method of claim 33, wherein the step of providing an optical bench substrate further
2 comprises fabricating alignment features for aligning the laser substrate and the array of edge-
3 receiving optical devices together so as to optically couple the array of surface-emitting lasers to
4 the array of edge-receiving optical devices.

1 35. A system for conditioning the output signals of one or more surface-emitting lasers, the
2 system comprising:
3 an optical bench substrate;
4 the one or more surface-emitting lasers being mounted on the optical bench substrate;
5 and
6 one or more edge-receiving optical devices positioned on the optical bench substrate so
7 as to receive the output signals from the one or more surface-emitting lasers.

1 36. The system of claim 35, wherein the one or more surface-emitting lasers are fabricated in
2 a laser substrate, and wherein the optical bench substrate photolithographically defines a slot for
3 receiving an edge of the laser substrate so as to optically couple the one or more surface-emitting
4 lasers to the one or more edge-receiving optical devices.

1 37. The system of claim 36, wherein the optical bench substrate further photolithographically
2 defines alignment features for aligning the laser substrate and the one or more edge-receiving
3 optical devices together so as to optically couple the one or more surface-emitting lasers to the
4 one or more edge-receiving optical devices.

1 38. The system of claim 36, wherein the slot is fabricated in the optical bench substrate by
2 electron beam lithography.

1 39. The system of claim 36, wherein the alignment features are fabricated in the optical
2 bench substrate by electron beam lithography.

1 40. The system of claim 35, wherein the one or more edge-receiving optical devices are
2 monolithically fabricated on the optical bench substrate.

1 41. The system of claim 35, wherein the optical bench substrate is a silicon optical bench.

1 42. The system of claim 35, wherein the system is for use in one of data communications and
2 telecommunications.

1 43. The system of claim 35, wherein the system is further for measuring radiation absorption
2 by a measurement species, the system further comprising:
3 one or more sources of single mode laser radiation comprising the one or more surface-
4 emitting lasers, respectively; and
5 a detector for detecting the single mode laser radiation after passage thereof through a
6 quantity of said measurement species.

1 44. The system of claim 43, wherein the laser radiation is infrared laser radiation.

1 45. The system of claim 43, wherein the measurement species is a gas disposed in a
2 measurement cell.

1 46. The system of claim 43, wherein the measurement species is an unconfined gas.

1 47. The system of claim 43, wherein the measurement species is one or more of human
2 blood, a bacterial species, and a viral species.

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